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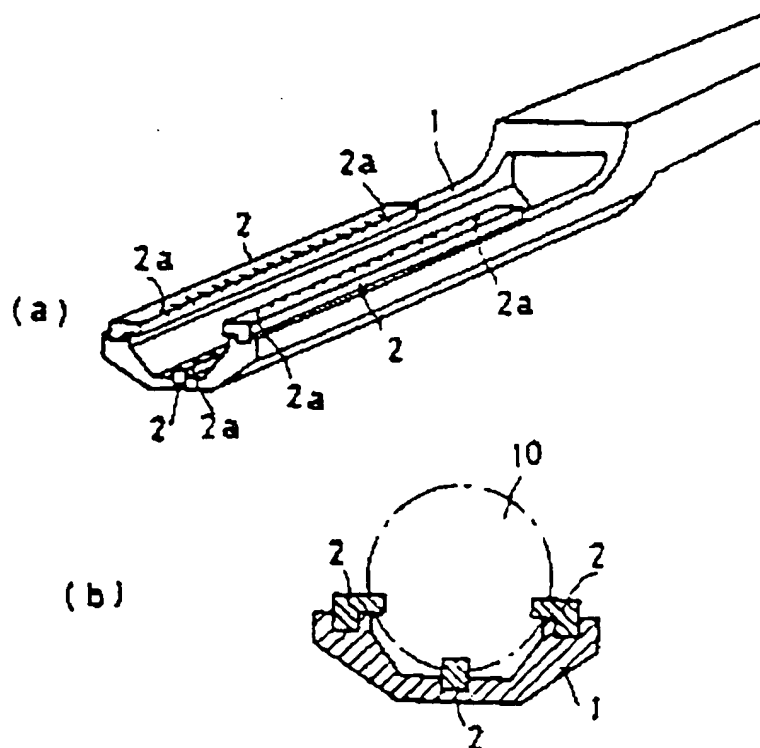
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**(54) CANTILEVER FOR
SEMICONDUCTOR
TREATMENT**

(57) Abstract:

PURPOSE: To eliminate a deflection and a decrease in a strength by detachably attaching a plurality of quartz glass rods, each with many wafer supporting grooves formed in it, on a cantilever body made of silicon carbide, a jig for semiconductor diffusion.

CONSTITUTION: The end of a cantilever body 1 made of silicon carbide is formed in a recess corresponding to the shape of a wafer, and three engaging grooves, two of which are at the upper end and one of which is at a bottom, are formed along a longitudinal direction. A quartz glass rod 2 formed with many wafer supporting grooves 2a is detachably attached to the grooves, and a wafer 10 is supported by the grooves 2a. Thus, since a wafer boat



is not used, the deflection of a cantilever does not almost become a problem, and since the supporting groove is not formed on the body, its strength is not decreased. Further, since the rod 2 is detachable, it can be easily cleaned and replaced.

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